<table>
<tr><th colspan="3">MONDAY 5</th><th colspan="3">TUESDAY 6</th><th colspan="3">WEDNESDAY 7</th><th>THURSDAY 8</th></tr>
<tr><td colspan="3">Welcome
Felip Sandiumenge</td><td colspan="3" rowspan="2">High resolution EM – I
M-J Casanove</td><td colspan="3" rowspan="2">Tomography
J. Arbiol</td><td rowspan="2">HAADF
M. Varela</td></tr>
<tr><td colspan="3">The Electron Microscope, a tool for nanostructure characterization
G. Van Tendeloo</td></tr>
<tr><td colspan="3">Electron diffraction
J. Portillo</td><td colspan="3">High resolution EM – II
M-J Casanove</td><td colspan="3">EELS/EFTEM
B. Warot</td><td>EELS mapping
M. Varela</td></tr>
<tr><td colspan="3">Break</td><td colspan="3">Break</td><td colspan="3">Break</td><td>Break</td></tr>
<tr><td colspan="3">Contrast in the TEM
F. Peiró</td><td colspan="3">Electron holography
E. Snoeck</td><td colspan="3">EDS
J. Portillo</td><td>Lab: sample preparation</td></tr>
<tr><td colspan="3">Lunch</td><td colspan="3">Lunch</td><td colspan="3">Lunch</td><td>Lunch</td></tr>
<tr><td>Group1</td><td>Group2</td><td>Group3</td><td>Group1</td><td>Group2</td><td>Group3</td><td>Group1</td><td>Group2</td><td>Group3</td><td></td></tr>
<tr><td>TEM1</td><td>TEM2</td><td>TEM3</td><td>TEM3</td><td>TEM1</td><td>TEM2</td><td>TEM2</td><td>TEM3</td><td>TEM1</td><td></td></tr>
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<tr><td colspan="3">PC1</td><td colspan="3">PC2</td><td colspan="3">PC3</td><td></td></tr>
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PC sessions:

PC1: Simulation of defects and interfaces
PC2: HREM: strain analysis
PC3: EELS data processing

Microscope sessions:

TEM1: Diffraction and Image – CM30
TEM2: EELS-EFTEM - J2010F
TEM3: Analytical TEM (EDX, HAADF) – J2100